

Refine Search

Search Results -

Terms	Documents
(substrate and microelectromechanical and (fluid or gas) and (seal or sealed or encapsulate) and periphery and gap).clms.	0

Database:

- US Pre-Grant Publication Full-Text Database
- US Patents Full-Text Database
- US OCR Full-Text Database
- EPO Abstracts Database
- JPO Abstracts Database
- Derwent World Patents Index
- IBM Technical Disclosure Bulletins

Search:

L14

Refine Search

Recall Text

Clear

Interrupt

Search History

DATE: Wednesday, June 21, 2006 [Printable Copy](#) [Create Case](#)

<u>Set</u> <u>Name</u> side by side	<u>Query</u>	<u>Hit</u> <u>Count</u>	<u>Set</u> <u>Name</u> result set
DB=PGPB; PLUR=YES; OP=ADJ			
L14	(substrate and microelectromechanical and (fluid or gas) and (seal or sealed or encapsulate) and periphery and gap).clms.	0	L14
DB=USPT; PLUR=YES; OP=ADJ			
L13	L9 and gap	67	L13
DB=PGPB; PLUR=YES; OP=ADJ			
L12	L9 and gap	0	L12
L11	L7 and gap	105	L11
L10	L7 and (gap or void or space or trench or groove)	154	L10
DB=USPT; PLUR=YES; OP=ADJ			
L9	L8 and (gap or void or space or trench or groove)	127	L9
L8	L4 and periphery	144	L8
DB=PGPB; PLUR=YES; OP=ADJ			
L7	L3 and periphery	163	L7
DB=JPAB; PLUR=YES; OP=ADJ			
L6	substrate and microelectromechanical and (fluid or gas) and (seal or sealed or encapsulate)	0	L6

DB=EPAB; PLUR=YES; OP=ADJ

L5 substrate and microelectromechanical and (fluid or gas) and (seal or sealed or encapsulate)

0 L5

DB=USPT; PLUR=YES; OP=ADJ

L4 substrate and microelectromechanical and (fluid or gas) and (seal or sealed or encapsulate)

801 L4

DB=PGPB; PLUR=YES; OP=ADJ

L3 substrate and microelectromechanical and (fluid or gas) and (seal or sealed or encapsulate)

1044 L3

DB=TDBD; PLUR=YES; OP=ADJ

L2 substrate and microelectromechanical and (fluid or gas) and (seal or sealed or encapsulate)

0 L2

DB=DWPI; PLUR=YES; OP=ADJ

L1 substrate and microelectromechanical and (fluid or gas) and (seal or sealed or encapsulate)

10 L1

END OF SEARCH HISTORY